

1 ABSTRACT OF THE DISCLOSURE

2 Semiconductor processors, sensors, semiconductor processing
3 systems, semiconductor workpiece processing methods, and turbidity
4 monitoring methods are provided. According to one aspect, a
5 semiconductor processor includes a process chamber configured to
6 receive a semiconductor workpiece for processing; a supply connection
7 in fluid communication with the process chamber and configured to
8 supply slurry to the process chamber; and a sensor configured to
9 monitor the turbidity of the slurry. Another aspect provides a
10 semiconductor workpiece processing method including providing a
11 semiconductor process chamber; supplying slurry to the semiconductor
12 process chamber; and monitoring the turbidity of the slurry using a
13 sensor.

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